

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Patent Application of: )  
Koichiro TANAKA, et al. ) Group Art Unit: 3742  
Application No. 10/769,820 ) Examiner: Samuel M. Heinrich  
Filed: February 3, 2004 ) Confirmation No. 9528  
For: LASER IRRADIATION STAGE, LASER )  
IRRADIATION OPTICAL SYSTEM, LASER  
IRRADIATION APPARATUS, LASER  
IRRADIATION METHOD, AND METHOD OF  
MANUFACTURING A SEMICONDUCTOR  
DEVICE )

**SUBMISSION OF FORMAL DRAWINGS**

**MAILSTOP: Issue Fee**

Commissioner for Patents  
P.O. Box 1450  
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Sir:

Submitted herewith are four (4) sheets of formal drawings, consisting of Figures 4A, 4B, 6, 7A, 7B, 8A and 8B, for filing in the subject application.

Respectfully submitted,

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